

<b>Notice of References Cited</b>	Application/Control No. 10/041,896	Applicant(s)/Patent Under Reexamination KRAUS ET AL.	
	Examiner Yennhu B Huynh	Art Unit 2813	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,218,293 B1	04-2001	Kraus et al.	438/644
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Herng Liu, "The Surface Chemistry of Aluminum Nitride MOCVD on Alumina Using Trimethylaluminum and Ammonia As Precursors", Surface Science 320, pp. 145-160, 1994.
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	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.